

<b>Notice of References Cited</b>	Application/Control No. 10/735,742	Applicant(s)/Patent Under Reexamination LIM ET AL.	
	Examiner Stanetta D. Isaac	Art Unit 2812	Page 1 of 1

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Stanley Wolf and Tauber N. Richard, Silicon Processing For The VLSI Era, 2000, Lattice Press, Second Edition, pgs. 277-283
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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